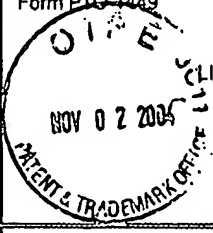
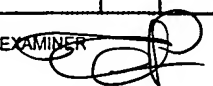


Form PTO 4449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1828		SERIAL NO. 10/071,425	
 <p style="text-align: center;">LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)</p>				APPLICANT: Terry L. Gilton et al.			
				FILING DATE February 8, 2002		GROUP 2813	
<b>U.S. PATENT DOCUMENTS</b>							
Examiner's Initials	AA	Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
	AA						
	AB						
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<b>FOREIGN PATENT DOCUMENTS</b>							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes    No
	AJ						
	AK						
	AL						
<b>OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)</b>							
TSP	AM		Lee et al., <i>Lithographic Properties of SiN<sub>x</sub> and Se<sub>75</sub>Ge<sub>25</sub> Thin Films as the Low-Energy Ion-Beam Resist</i> ,				
			5 <sup>th</sup> International Conference on Properties and Applications of Dielectric Materials, Seoul, Korea				
	AN		(May 25-30, 1997) pp. 635-638.				
	AO						
EXAMINER 		DATE CONSIDERED    5/29/05					
<p><small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small></p>							